SYSTEM AND METHOD FOR DETERMINING THE CENTER OF A WAFER ON A WAFER TABLE

ABSTRACT OF THE INVENTION

A method for determining the center (62) of a silicon wafer (54) on a wafer table (14) is provided. The method includes measuring silicon wafer data with a sensor (22). The silicon wafer data is received at a wafer center computing system (38). The coordinates of the wafer center (Xw,Yw) in a wafer table Cartesian coordinate system (72) are computed. The coordinates of the edge of the silicon wafer (54) are then determined from the wafer center coordinates (Xw,Yw).

Figure 1